

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

First Named  
Inventor : David W. Duquette

Appln. No. : 09/767,199

Filed : January 22, 2001

For : IMPROVED LASER ALIGN SENSOR  
WITH SEQUENCING LIGHT  
SOURCES

Docket No.: C34.12-0021

Group Art Unit: 2877

Examiner:

RECEIVED  
MAY 16 2001  
TC 2800 MAIL ROOM

### SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
Washington, D.C. 20231

I HEREBY CERTIFY THAT THIS PAPER IS BEING  
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ASSISTANT COMMISSIONER FOR PATENTS,  
WASHINGTON, D.C. 20231, THIS

DAY OF May, 2001  
  
PATENT ATTORNEY

Sir:


The patents or publications listed on the enclosed PTO Form-1449 are submitted pursuant to 37 C.F.R. § 1.97. Copies of the patents or publications cited are enclosed.

The Director is authorized to charge any fee deficiency required by this paper or credit any overpayment to Deposit Account No. 23-1123.


Respectfully submitted,

WESTMAN, CHAMPLIN & KELLY, P.A.

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FORM PTO-1449	Atty. Docket No.: C34.12-0021	Appl. No.: 09/767,199
<p>LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT</p> 	First Named Inventor:	
	David W. Duquette	
	Filing Date	Group Art:
	January 22, 2001	2877

## U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Date	Name	Class	Sub Class	Filing Date If Appropriate
AA	5,467,186	11/14/95	Indo et al.	356	150	
AB	5,570,993	11/05/96	Onodera et al.	414	783	
AC	5,741,114	04/21/98	Onodera	414	783	
AD	5,749,142	05/12/98	Hanamura	29	833	
AE						
AF						
AG						
AH						
AI						
AJ						

## FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Class	Sub Class	Translation Yes No
AK	6-21697	01/28/94	Japan			(Abstract Only)
AL	9-293998	04/26/96	Japan			X
AM						
AN						

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AO	
AP	
AQ	
AR	

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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.